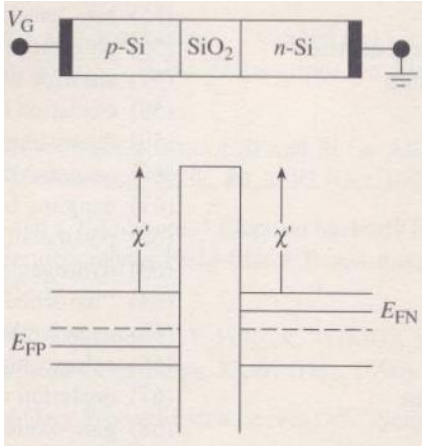


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5. (15 points, 3 points each) 1. The energy band diagram for a  $p$ -Si/SiO<sub>2</sub>/ $n$ -Si capacitor (SOS-C) under flat-band conditions is given below. The SOS-C is ideal except for a non-zero work function difference.  $T = 300$  K,  $N_A$  ( $p$ -side) =  $N_D$  ( $n$ -side) =  $10^{15}$  cm<sup>-3</sup>,  $n_i = 10^{10}$  cm<sup>-3</sup>, oxide thickness =  $5 \times 10^{-6}$  cm, and area  $A_G = 10^{-3}$  cm<sup>2</sup>.



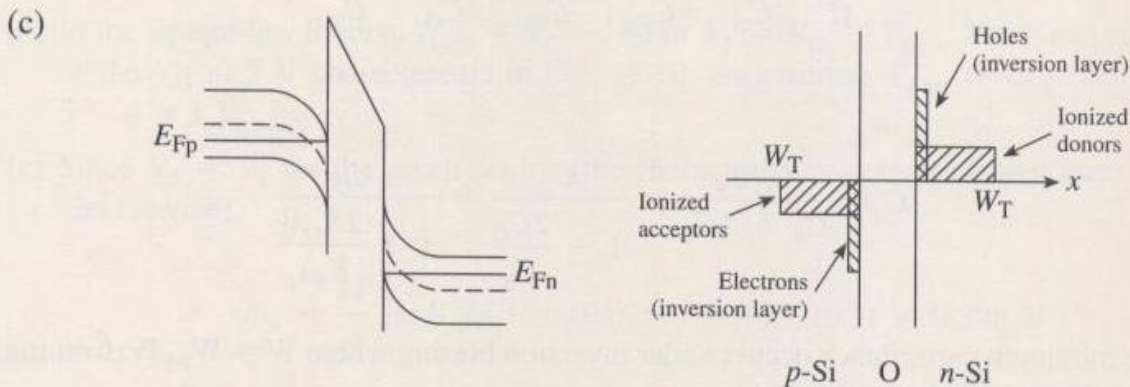
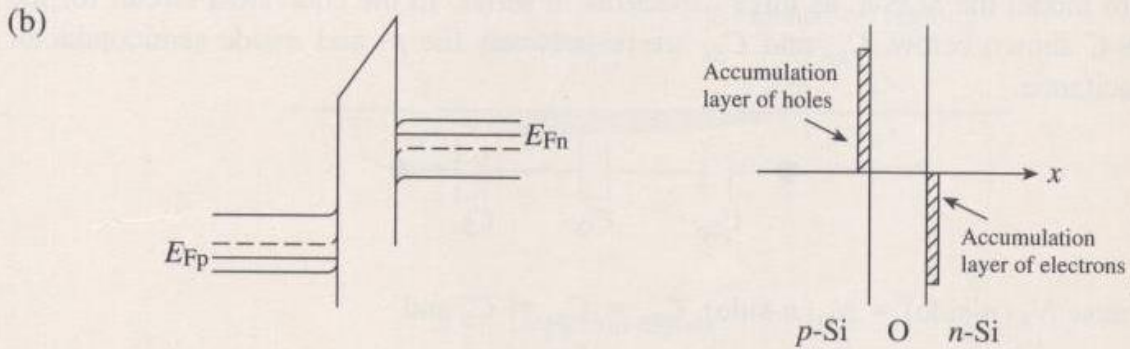
(a) To achieve the pictured state, there must of course be a non-zero voltage applied to the SOS-C gate. What is it? Give both the polarity and magnitude of  $V_G$ . Give both a symbolic and numerical answer.

(b) Sketch the energy band diagram and the associated block charge diagram for the SOS-C when a *large positive* gate voltage (say  $V_G > 5V$ ) is applied to the device.

(c) Same as (b) except now a *large negative* gate voltage is applied to the gate.

$$(a) V_G = \frac{1}{q}(E_{FN} - E_{FP}) = \frac{1}{q}[(E_{FN} - E_i) + (E_i - E_{FP})] = \frac{kT}{q} [\ln(N_D/n_i) + \ln(N_A/n_i)]$$

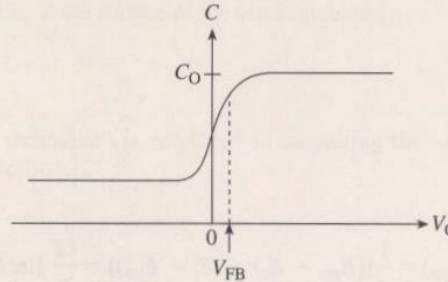
$$= 2(0.0259) \ln(10^{15}/10^{10}) = \mathbf{0.596 \text{ V}}$$



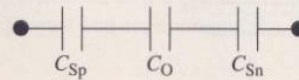
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(d) Make a sketch of the high-frequency  $C-V_G$  characteristic to be expected. Explain how you arrived at your sketch.

(d) When  $V_G > 0$ , both semiconductor components are accumulated. Thus  $C$  approaches  $C_O$  at large positive gate biases. When  $V_G < 0$ , the two semiconductor components first deplete and then invert. Inversion occurs at the same bias voltage for the two sides of the SOS-C because  $N_A(p\text{-side}) = N_D(n\text{-side})$ . The high-frequency capacitance is therefore expected to smoothly decrease to  $C_{\min}$  at large negative biases. As sketched below, the deduced characteristic should look very similar to a standard  $n$ -bulk high-frequency MOS-C  $C-V$  curve.



(e) Reflecting on the answers to previous parts of the problem, particularly part (c), we are led to model the SOS-C as three capacitors in series. In the equivalent circuit for the SOS-C shown below,  $C_{Sp}$  and  $C_{Sn}$  are respectively the  $p$ - and  $n$ -side semiconductor capacitance.



Because  $N_A(p\text{-side}) = N_D(n\text{-side})$ ,  $C_{Sp} = C_{Sn} = C_S$  and

$$\frac{1}{C} = \frac{1}{C_O} + \frac{1}{C_{Sp}} + \frac{1}{C_{Sn}} = \frac{1}{C_O} + \frac{2}{C_S}$$

or

$$C = \frac{C_O C_S}{C_S + 2C_O} = \frac{C_O}{1 + \frac{2C_O}{C_S}} = \frac{C_O}{1 + \frac{2K_O W}{K_S x_o}}$$

The minimum capacitance occurs under inversion biasing where  $W = W_T$ . Performing the indicated computations gives

$$\phi_F = \frac{kT}{q} \ln(N_A/n_i) = (0.0259) \ln(10^{15}/10^{10}) = 0.298 \text{ V}$$

$$W_T = \left[ \frac{2K_S \epsilon_0}{qN_A} (2\phi_F) \right]^{1/2} = \left[ \frac{2(11.8)(8.85 \times 10^{-14})(0.596)}{(1.6 \times 10^{-19})(10^{15})} \right]^{1/2} = 8.82 \times 10^{-5} \text{ cm}$$

$$C_O = \frac{K_O \epsilon_0 A_G}{x_o} = \frac{(3.9)(8.85 \times 10^{-14})(10^{-3})}{(5 \times 10^{-6})} = 69.0 \text{ pF}$$

and

$$C_{\min} = \frac{C_O}{1 + \frac{2K_O W_T}{K_S x_o}} = \frac{69.0}{1 + \frac{2(3.9)(8.82 \times 10^{-5})}{(11.8)(5 \times 10^{-6})}} = 5.45 \text{ pF}$$

(e) Determine the minimum capacitance exhibited by the device. Give both a symbolic and numerical answer.

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(9 points, 3 points each) 2. Apply constant-field scaling to the ideal current-voltage relations of MOSFETs in both the saturation and nonsaturation bias region. Assume the scaling factor  $k = 0.6$ , e.g., the new gate length  $L$  is now  $0.6 L$ .

(a) How does the drain current scale in each bias region? Explain.

7.1

(a) Non-saturation region

$$I_D = \frac{1}{2} \mu_n C_{ox} \left( \frac{W}{L} \right) \left[ 2(V_{GS} - V_T)V_{DS} - V_{DS}^2 \right]$$

We have

$$C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} \Rightarrow \frac{C_{ox}}{k}$$

and

$$W \Rightarrow kW, L \Rightarrow kL$$

also

$$V_{GS} \Rightarrow kV_{GS}, V_{DS} \Rightarrow kV_{DS}$$

So

$$I_D = \frac{1}{2} \mu_n \left( \frac{C_{ox}}{k} \right) \left( \frac{kW}{kL} \right) \left[ 2(kV_{GS} - V_T)kV_{DS} - (kV_{DS})^2 \right]$$

Then

$$\underline{I_D \Rightarrow \approx kI_D}$$

In the saturation region

$$I_D = \frac{1}{2} \mu_n \left( \frac{C_{ox}}{k} \right) \left( \frac{kW}{kL} \right) \left[ kV_{GS} - V_T \right]^2$$

Then

$$\underline{I_D \Rightarrow \approx kI_D}$$

(b)

$$\underline{P = I_D V_{DS} \Rightarrow (kI_D)(kV_{DS}) \Rightarrow k^2 P}$$

(b) How does the power dissipation per device scale in each bias region? Explain.

(c) Why is it important to develop "high  $\kappa$ " dielectric material to replace SiO<sub>2</sub>?  $\kappa$  here means dielectric constant (not the  $k$  above).

$C = \kappa/d$ . The ultimate limit of  $d$  is one or two atomic layers, and the practical limit to have a continuous film may be several times higher. If  $\kappa$  is high,  $d$  can be thicker, which is more practical.